

First Named Inventor	Wang Zhongze	INFORMATION DISCLOSURE STATEMENT FORM PTO-1449
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TUP	S. Wolf et al, "Silicon Epitaxial Film Growth," <u>Silicon Processing for the VLSI Era</u> , Vol. 1, 1986, pp. 124-160.		

Examiner Signature	<i>W. Ivan March</i>	Date Considered	6/2/03
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*Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.